

## Double gradient multilayer

Idea: Figured optics for broad energy bands

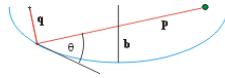
- Incident angle variation followed by lateral gradient
- Energy band defined by depth-gradient
- Fixed-exit focusing device for variable energies ("micro-spectroscopy")

Example: Elliptic mirror with [Ru/B<sub>4</sub>C]<sub>35</sub> multilayer coating to be used at energy range 6000-13000 eV with ΔE/E ≈ 16%

Lateral gradient for mean energy

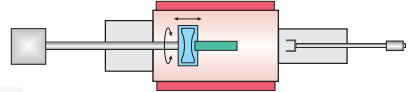
$$\Lambda = \frac{\lambda \cdot m}{2\sqrt{n^2 - \cos^2 \theta}}$$

$$\sin \theta = \frac{b}{\sqrt{pq}}$$



## Deposition system

- Ar pressure: 1.3 × 10<sup>-3</sup> mbar
- Polarization voltage: U = -500...-2000 V (DC/RF)
- Particle flux: R = 0.02...0.10 am/s
- Deposition temperature: T<sub>dep</sub> ≈ 100°C

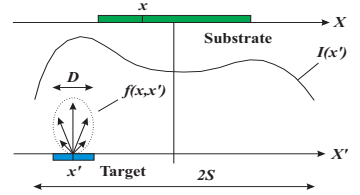


- Distributed Electron Cyclotron Resonance (DECR) plasma sputtering
- 3 target positions, rotation and linear movement

## Thickness control

Basic model assumptions

- Total particle flux ∝ weighted sum of Gaussian (G) + Lorentzian (L)
- Rate R ∝ ion current I at U=const
- Local velocity v → local "exposure time" dt = dx/v
- Integration over total stroke 2S of target movement



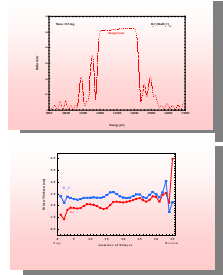
## Depth-graded multilayers

Goal

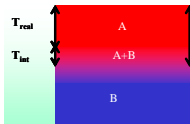
- Design multilayer with particular reflectivity profile
- R = R(θ) for E = const.
- R = R(E) for θ = const.
- Find vertical composition profile: 71 independent layers

Design method

- Choose appropriate starting solution
- Apply fit algorithm to optimize the structure



## Interdiffusion thickness determination

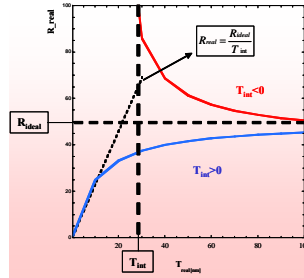


Thickness definition:

$$T_{ideal} = T_{real} + T_{int}$$

Sputtering rates definition:

$$R_{real} = R_{ideal} * \frac{T_{real}}{T_{real} + T_{int}}$$



Periodic multilayer

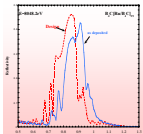
- Ideal speed determination
- Interdiffusion layer for each material

Non periodic multilayer

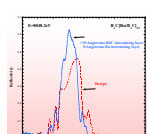
- Shift on angle → interdiffusion of B4C
- Broad peak → interdiffusion of B4C

## Experimental aspects

Regular compensation

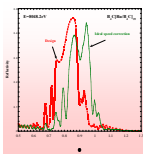


Interdiffusion compensation added



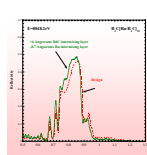
Tests and calibrations

- At E=8.048.2keV (Lab reflectometer energy)



Thickness control

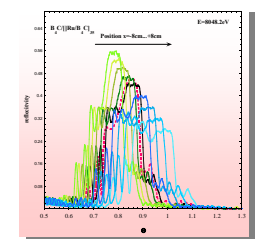
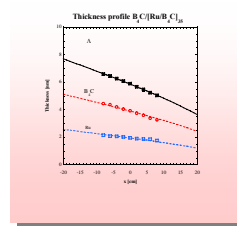
- Depth: variation of exposure time / total speed by analytical function or look-up table
- Lateral: modification of speed profile
- Both depth and lateral gradient possible



Required corrections

- Real film densities
- Layer interdiffusion → variable growth rate
- Machine drift → linear compensation

## Lateral gradient - Results



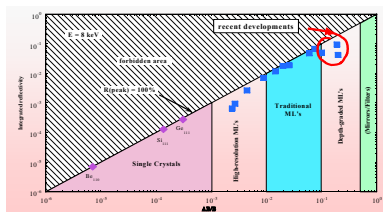
## Summary and perspectives

Advantages

- Focusing ML over a broad angle range
- Combination of lateral and depth gradient
- Focusing at fixed distance and variable energies

Future perspectives

- Integration into beamline optics
- Global optimization algorithm for both gradients



Bragg equation:

$$E = \frac{h \cdot c}{2 \cdot \Lambda \cdot \sqrt{n^2 - \cos^2 \theta}}$$

Elliptical mirror:

$$\sin \theta = \frac{b}{\sqrt{pq}}$$

$$E = \frac{h \cdot c}{2 \cdot \Lambda \cdot \sqrt{n^2 - 1 + \frac{b^2}{pq}}}$$

→ Dispersion "along ML mirror"

